



#93
DBWLR
3-21-00

500.37149X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: S. MAEDA et al.

Serial No.: 09/294,137

Filed: April 20, 1999

DEFECT INSPECTION METHOD AND APPARATUS

Art Unit: 2621

Examiner: B. Werner

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Technology Center 2600

AMENDMENT

**Assistant Commissioner for Patents
Washington, D.C. 20231**

March 11, 2002

Sir:

In response to the Office Action of October 11, 2001,
please amend the above-identified application as follows.

Submitted herewith is a credit card payment form in payment of the additional claim fee of \$72.00 due in connection with the filing of the present amendment.

IN THE CLAIMS

Cancel claims 3 and 16 without prejudice or disclaimer of
the subject matter thereof.

Amend claims 1-2, 4-15, and 17-30 as follows:

--1. (Amended) A method of inspecting patterns, comprising
the steps of:

picking up a first pattern formed on a substrate to produce a first image;